

- Introduction
- 1 vantages of SiC -M.Zetterling and M.Östling
- 2 Bulk and epitaxial growth of SiC N.Nordell
- 3 Ion implantation and diffusion in SiC A.Schöner
- 4 Wet and dry etching of SiC S.J.Pearton
- 5 Thermally grown and deposited thermoelectrics E.Ö.Sveinbjörnsson and C.-M.Zetterling
- 6 Schottky and ohmic contacts to SiC C.-M. Zetterling and S.-K.Lee and M.Östling
- 7 Devices in SiC C.-M.Zetterling S.M.Koo and M.Östling
- Appendix 1 Other resources
- Appendix 2 Glossary
- Index